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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Chih-Ming Ke

Application No.: 10/047,266 (CONF 4511)

Filed: 1/14/2002

Title: Reducing photoresist shrinkage via plasma treatment

Attorney Docket No.: 67,200-641

Group Art Unit:  
1765

Examiner:  
Kin Chan Chen

Commissioner for Patents  
Alexandria, VA 22313-1450

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Date:

9-29-03

  
Kathy Dixon

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action of July 2, 2003, please amend this application as follows and consider the following remarks.